Special Issue

Recent Advances in Silicon-Based MEMS Sensors and Actuators

Message from the Guest Editors

With the development of microelectronics technology and micro/nano manufacturing technology, Si-based MEMS sensors and actuators have progressed significantly. Due to their advantages of high precision, miniaturization and low power consumption, Si-based MEMS sensors and actuators have been widely applied in many fields, such as consumer electronics, automotive electronics, aerospace and military equipment. In order to showcase the latest research results in this field and promote technological innovation and application expansion, we would like to invite scholars, researchers and engineers from all over the world to contribute to this Special Issue.

This Special Issue will focus on research advances in Si-based MEMS sensors and actuators, covering novel sensing and execution mechanisms, advanced fabrication methods, performance optimization strategies and innovative applications in biomedical, environmental monitoring, intelligent manufacturing and communication electronics. We look forward to innovative, scientific and practical high-quality manuscripts, which will bring inspiration to the development of the Si-based MEMS field.

Guest Editors

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